

EECS 598-002 Nanophotonics and Nanoscale Fabrication
Winter 2006 Syllabus

Updated 1/26/05

No	Date	Topic	Details
Overview	1/5 Thu		
Nanophotonics	1/10 Tue	EM wave review	Review of Maxwell's Equations
	1/12 Thu		Concepts of fields and waves
	1/17 Tue		Radiation and evanescent waves
			Near fields and far fields
			Interface phenomena
			Diffraction and scattering basics
			Wave guiding
			Gain and loss
			Scaling and symmetry
	1/19 Thu	Concept of photons	Concepts of photons and a brief review of other
	1/24 Tue		quanta such as electrons and phonons
	1/26 Thu	Light-matter interaction	Introduction to light-matter interaction (1
	1/31 Tue		lecture):
	2/2 Thu		* How to determine $\epsilon(r)$?
	2/7 Tue		* The relationship to basic excitations.
2/9 Thu	Basic excitations and measurement of $\epsilon(r)$. (1		
2/14 Tue	lecture)		
2/16 Thu	Structure dependence of $\epsilon(r)$ overview (1 lecture)		
2/21 Tue	Surface effects (2 lectures):		
2/23 Thu	* Surface EM wave		
3/7 Tue	* Surface polaritons		
3/9 Thu	* Size dependence		
	Case studies (3 lectures):		
	* Quantum wells, wires, and dots		
	* Nanophotonics in microscopy		
	* Nanophotonics in plasmonics		
	Dispersion engineering (3 lectures):		
	* Material dispersion		
	* Waveguide dispersion (photonic crystals)		
Nanoscale Fabrication	3/14 Tue	Overview	
	3/16 Thu	Top-down approach	Optical lithography introduction
	3/21 Tue		Resolution enhancement techniques
	3/23 Thu		• phase shifted mask
			• optical proximity correction
		• interference lithography	
	3/28 Tue		Other lithographic techniques
		• Direct write	
		• Imprint	
	3/30 Thu		Thin film technologies and CMP/damascene
4/4 Tue		process	
4/6 Thu	Bottom-up approach	Strain induced nanostructures, chemical	
4/11 Tue		synthesis, selective-area epitaxy, atomic	
4/13 Thu		manipulation, etc.	

Term paper presentation	4/18 and 4/20 or 4/25 and 4/27
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